Process Development and Integration Lab

+ Measurements and Characterization

PDIL Presentations

PDIL Introduction

Thin-Si Platform

Si Wafer Replacement Platform

CIGS Platform

CdTe Platform

Atmospheric Processing Platform

M&C Platform and Standalone Capabilities

Data Integration

M&C Overview



NREL/PR-520-43173

Presented at the Solar Energy Technologies Program (SETP) Annual Program Review Meeting held April 22-24, 2008 in Austin, Texas

Austin Airport Marriott South

Austin, TX April 22-24, 2008



2008 Solar Annual Review Meeting

PDIL Overview

Brent P. Nelson



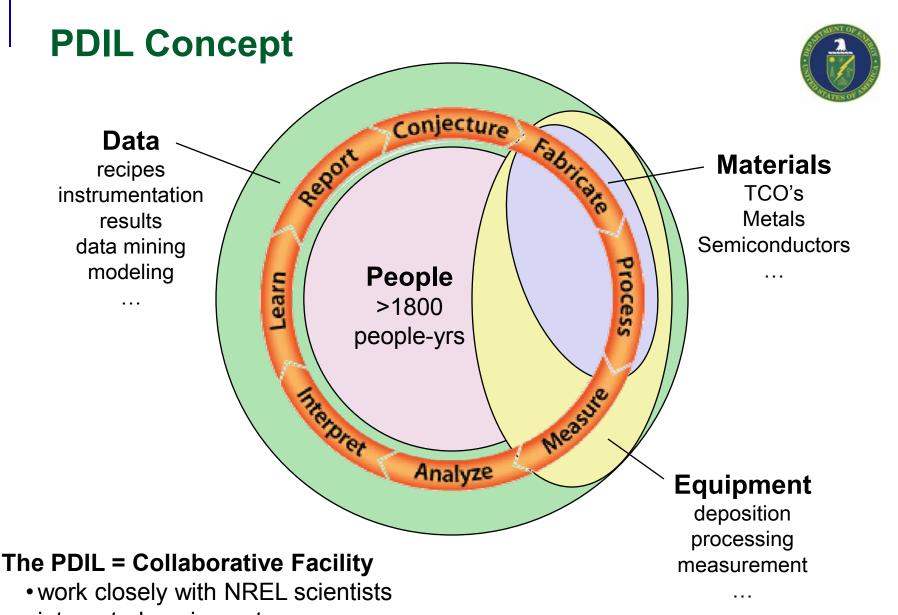
PDIL Vision



- Integrate deposition, characterization, and processing
 - Flexible and robust
 - Standardized transfer interface
 - Controlled sample ambient between tools

Benefits

- Answers to previously inaccessible research questions
- Control and characterization of critical surfaces (interfaces) and how their impact on subsequent layers
- Assess process-related source chemistry, surface chemistry and kinetics, and bulk reconstruction
- Grow layers and alter interfaces using controlled processes and transfer ambients (without exposure to air)
- Develop new techniques, methodologies, device structures, materials, and tools (growth, processing, and analytical)
- Improved collaborations with university and industry researchers



integrated equipment

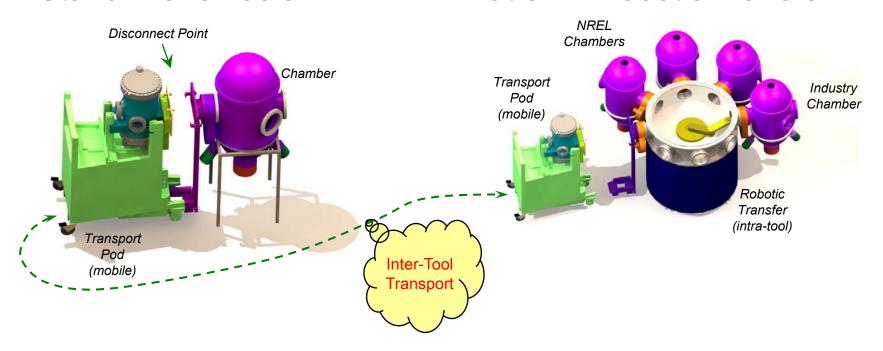
answer pressing PV related questions

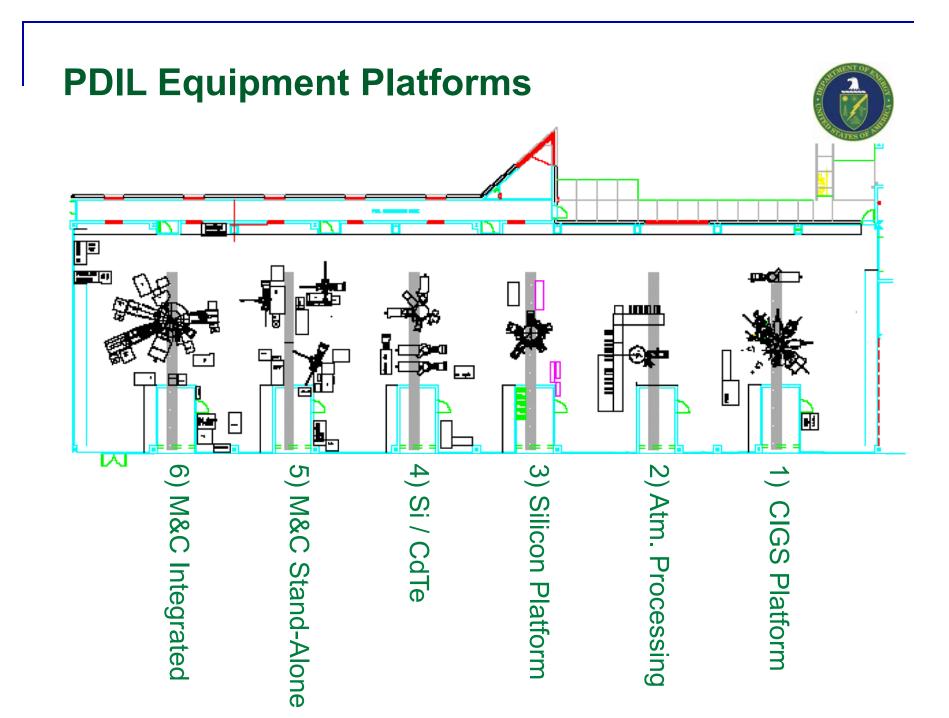
PDIL Implementation



Stand-Alone Tools

Platform: Robotic Transfer





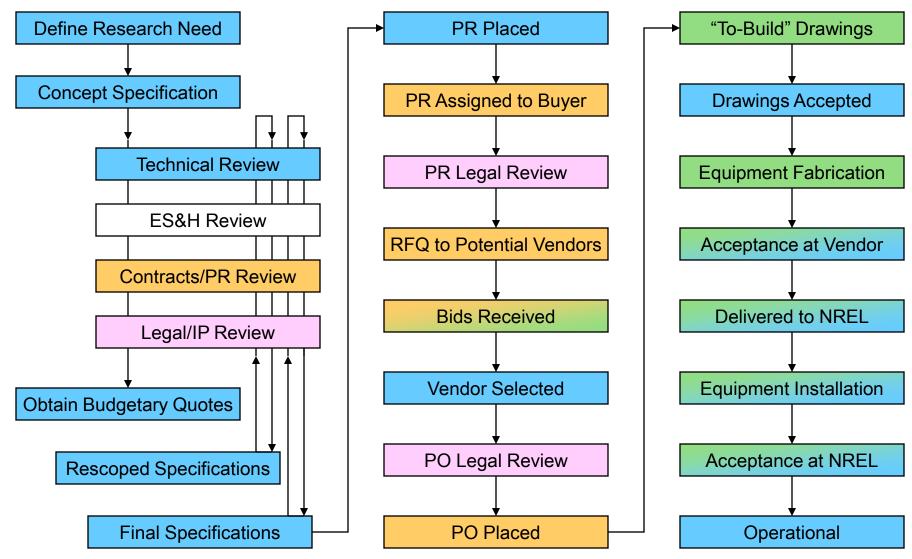
PV Technology Road Map Support



	PV Technology Road Maps								
	Wafer Si	Film Si	CPV	CdTe	CIGS	OPV	DSPV		
Platform	Š	Ξ	D	ပိ	\overline{o}	Ö	08		
Thin Si									
Wafer Rep.									
CIGS									
CdTe									
Atm. Proc.									
M&C Ind.									
M&C Cluster									

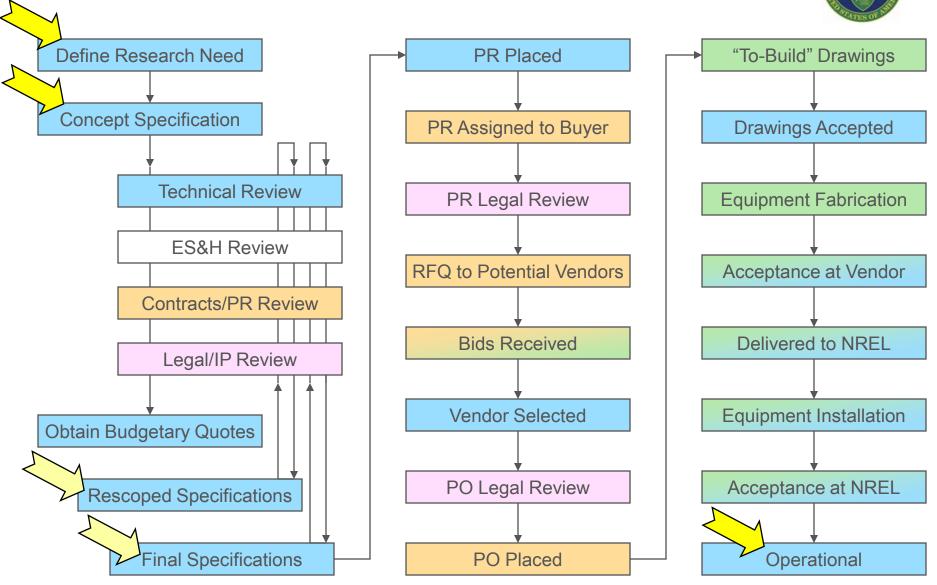
Steps in Custom Equipment Acquisition





Industrial Input





Thin-Silicon Platform



Qi Wang

	PV Technology Road Maps								
	Wafer Si	Film Si	CPV	CdTe	CIGS	OPV	DSPV		
Platform	×	Ξ	S	ပိ	Image: control of the	Ö	08		
Thin Si									
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